

## **Quick Start Guide: XeF<sub>2</sub> Etcher**

This short document is for helping users remember how to operate the tool. It does not replace the SOP nor training.

1. Check to see that XeF<sub>2</sub> valve is closed



- 2. Activate the tool on NEMO
- 3. Check to see that the tool is in 'Standby' mode

	XeE2 Etching System
Pulse Count	Anmber valve 1 Roughing Pumping valve 2 Nitrogen Gas Nitrogen Vart, #1 Nitrogen Vent, #2 Purging to Etching, #3 Nitrogen Vent, #2 Purging to Etching, #3 Nitrogen Vent, #2 Process control Borng Pessure (inforr) 3000 Purging Pessure (inforr) 10 Duration Time (second) 10 Duration

- 4. Fill in relevant information to the log sheet
- 5. Click 'Remove Wafer', unscrew black knob, and wait until step is complete





- 6. Open chamber, load sample(s), close chamber, then tighten black knob
- 7. Click 'Purge' and wait until step is complete
- 8. Open the XeF<sub>2</sub> valve



- 9. Click 'Pulse Etch' and wait until step is complete
- 10. Close the XeF<sub>2</sub> valve



- 11. Click 'Remove Wafer' and wait until step is complete
- 12. Unscrew the black knob and remove your sample(s)
- 13. If you have more samples, load them and repeat the procedure from step 6
- 14. If you are finished etching, close the chamber and tighten the black knob, and click 'Standby'
- 15. Wait 2 minutes
- 16. Fill in the 'End Status' on the log sheet and add any comments in 'Notes' (if you have any)
- 17. Deactivate tool on NEMO